

## Supplementary Information

# Designing zero-dimensional dimer-type all-inorganic perovskites for ultra-fast switching memory

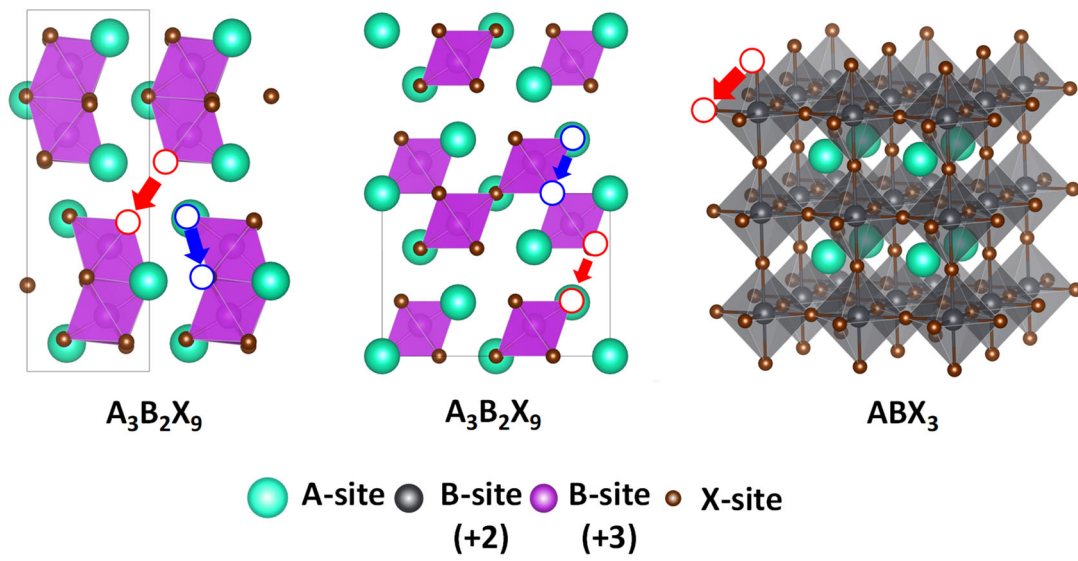
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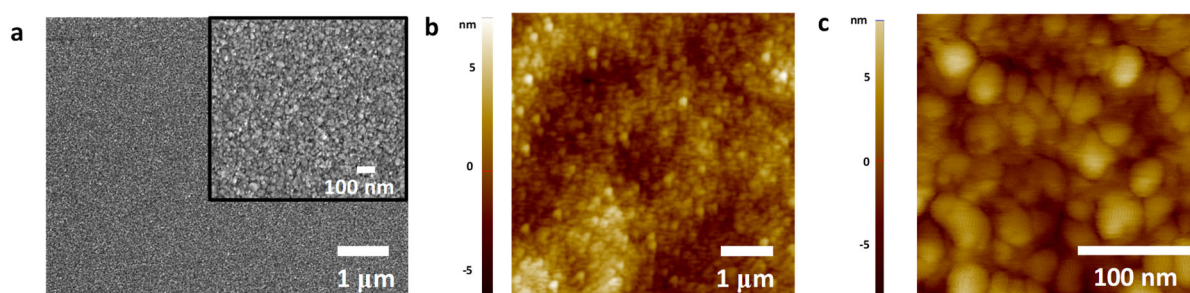
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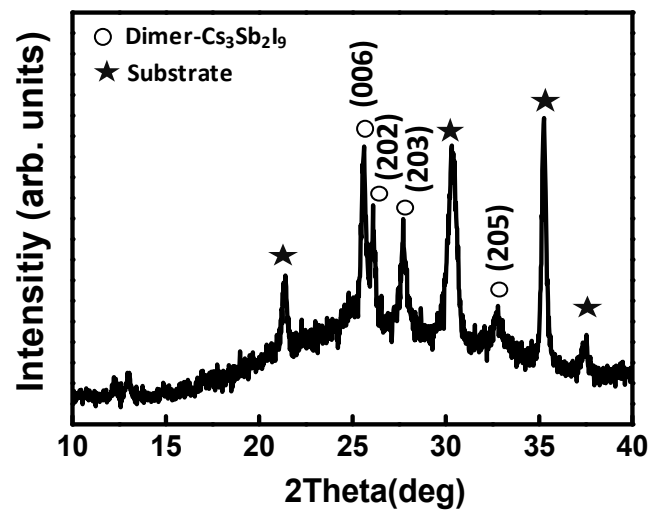
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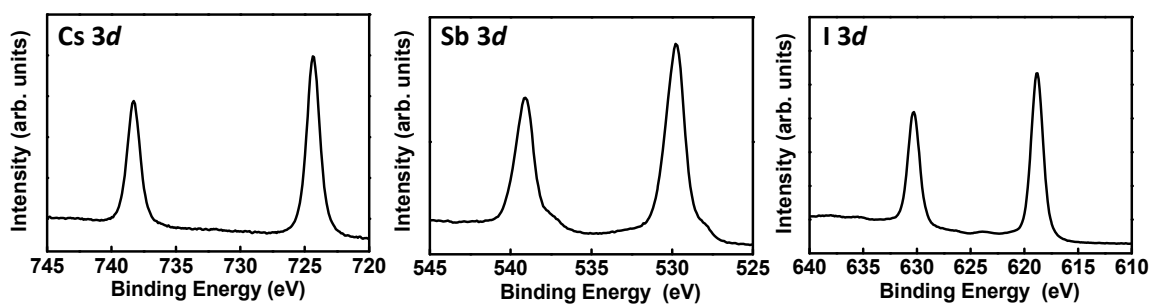
**Supplementary Figure 1.** Vacancy migration paths of HPs. Red circles and arrows represent inter-octahedron migration path. Blue circles and arrows represent intra-migration path. The rectangular boxes in schematic structures are the unit cell of crystal structure.



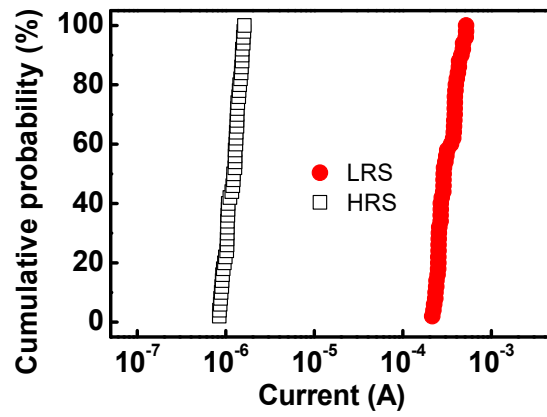
**Supplementary Figure 2.** (a) Plan-view SEM image of the dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  thin film (inset: magnified image). (b) AFM image of the surface of the dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$ . (c) Magnified AFM image of dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$ .



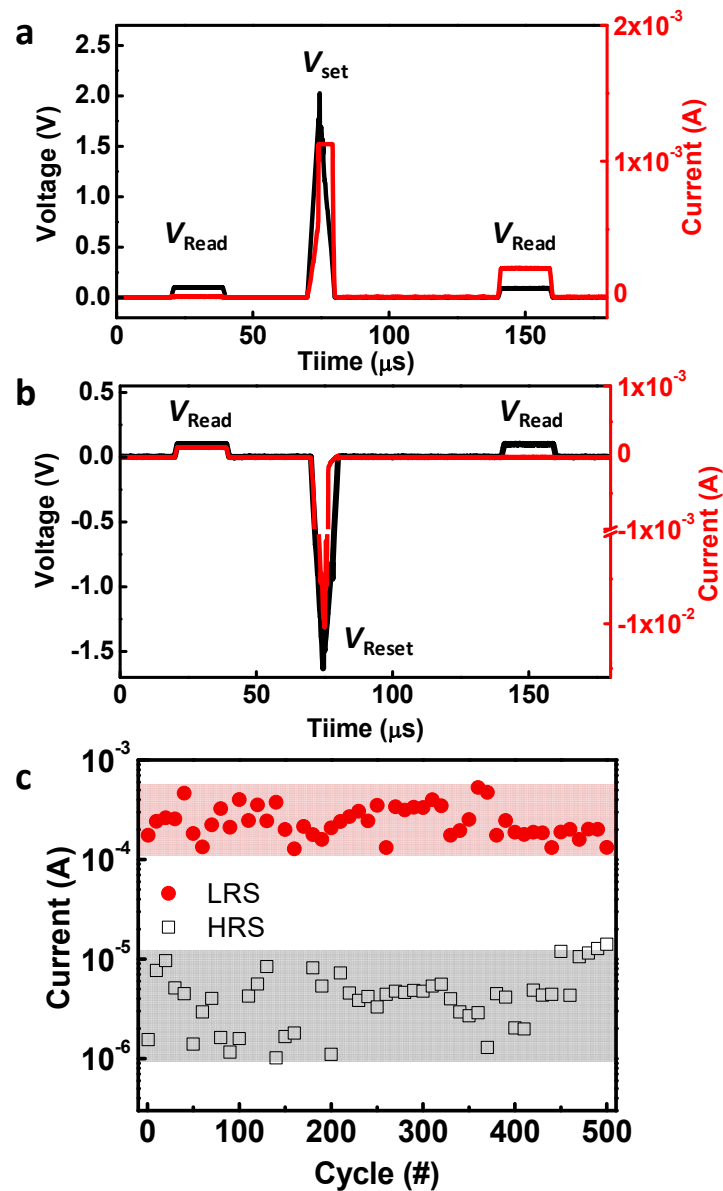
**Supplementary Figure 3.** XRD pattern of the dimer-Cs<sub>3</sub>Sb<sub>2</sub>I<sub>9</sub> thin film on ITO.



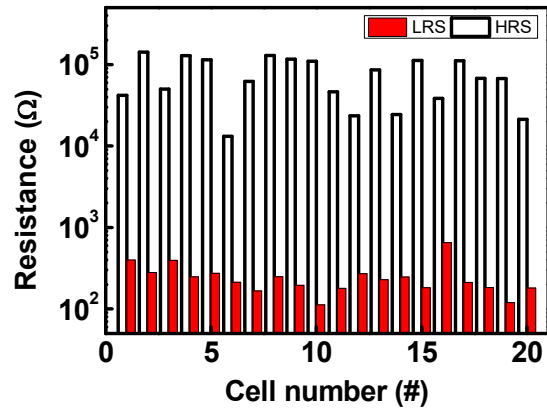
**Supplementary Figure 4.** XPS spectra of dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  thin film.



**Supplementary Figure 5.** Cumulative probability distributions of the resistance states during 50 consecutive voltage sweeps ( $0\text{ V} \rightarrow 1\text{ V} \rightarrow 0\text{ V} \rightarrow -1\text{ V} \rightarrow 0\text{ V}$ ). The resistances of LRS and HRS are obtained at a read voltage of  $0.1\text{ V}$ .

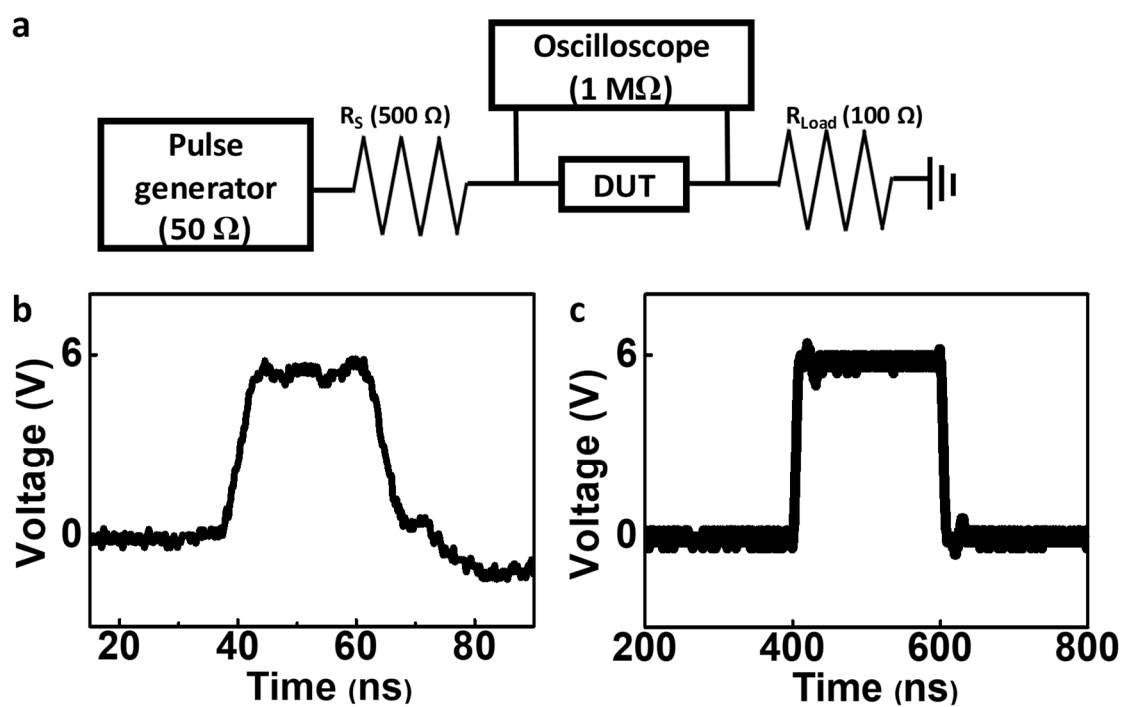


**Supplementary Figure 6.** Application of voltage pulses for (a) set and (b) reset processes. Positive triangular pulses that had a peak voltage of 2 V for the set process, and negative triangular pulses that had a peak of -1.6 V for the reset process, and the change of current level is measured under a read voltage of 0.1 V. (c) Endurance of dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  RSM device.

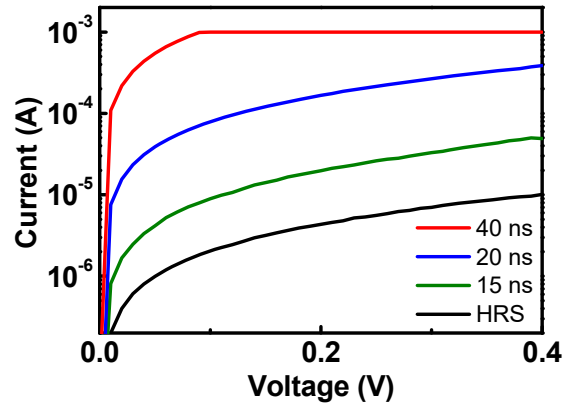


**Supplementary Figure 7.** Device-to-device variation of the dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  RSM device. The resistance states of 20 devices are measured at a read voltage of 0.1 V.

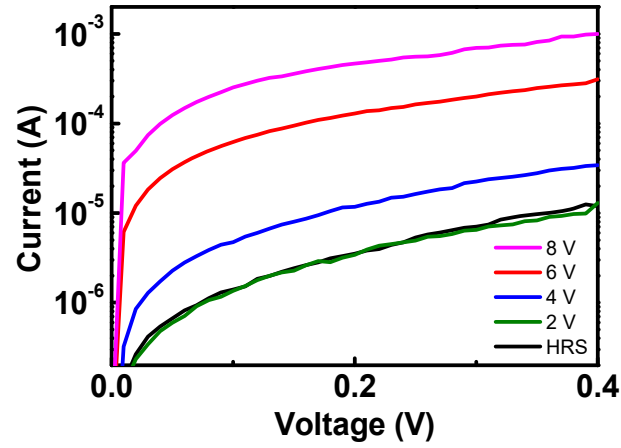




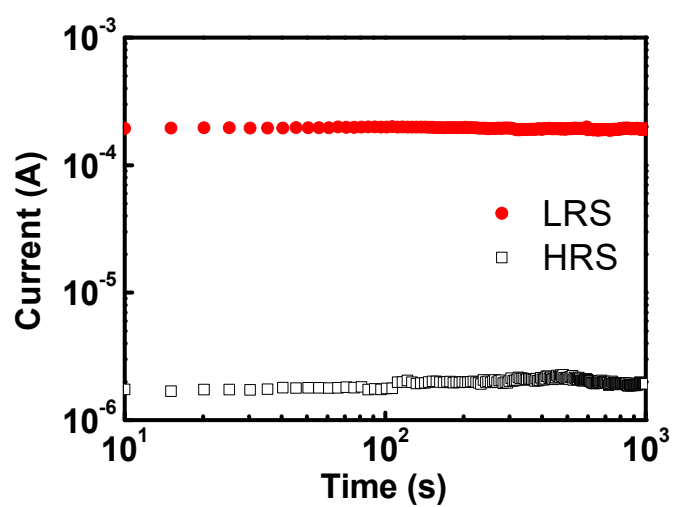
**Supplementary Figure 8.** a. Measurement scheme for pulse application. The waveforms of applied b. 20 ns and c. 200 ns pulses.



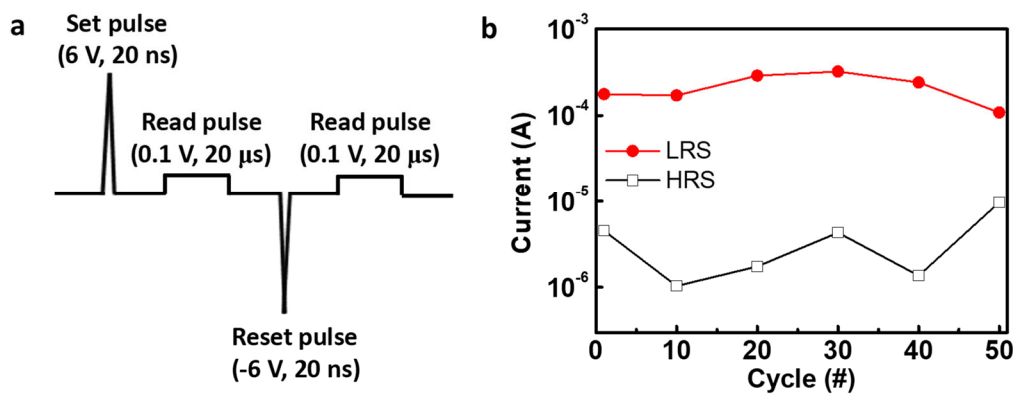
**Supplementary Figure 9.**  $I$ - $V$  characteristics of the dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  RSM by applying set pulses (6 V) with different pulse widths (15 ns, 20 ns, and 40 ns).



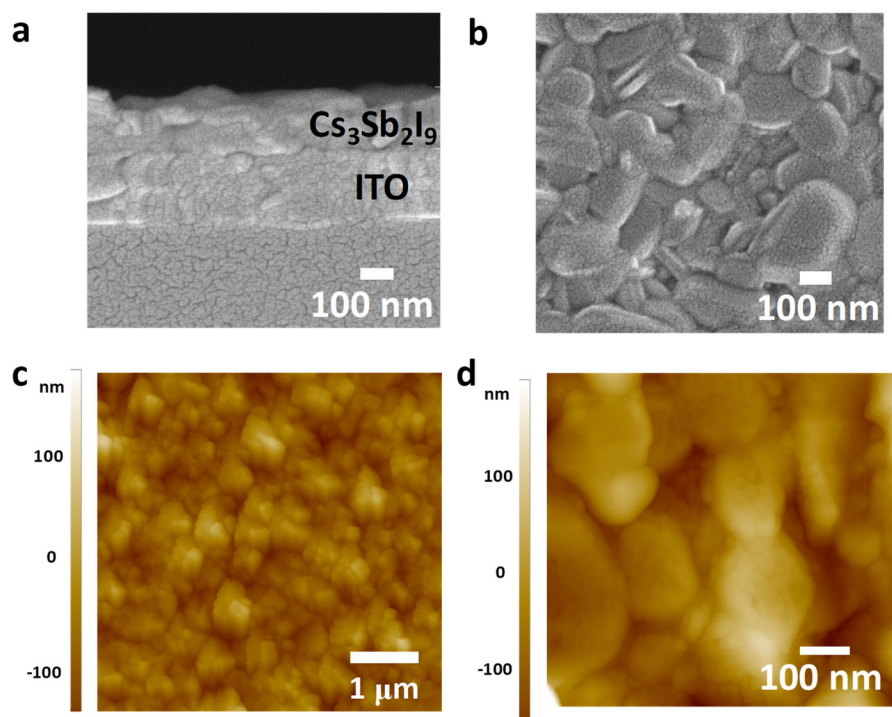
**Supplementary Figure 10.** *I-V* characteristics of the dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  RSM by application of set pulses (20 ns) with different voltage amplitudes (2 V, 4 V, 6 V, and 8 V).



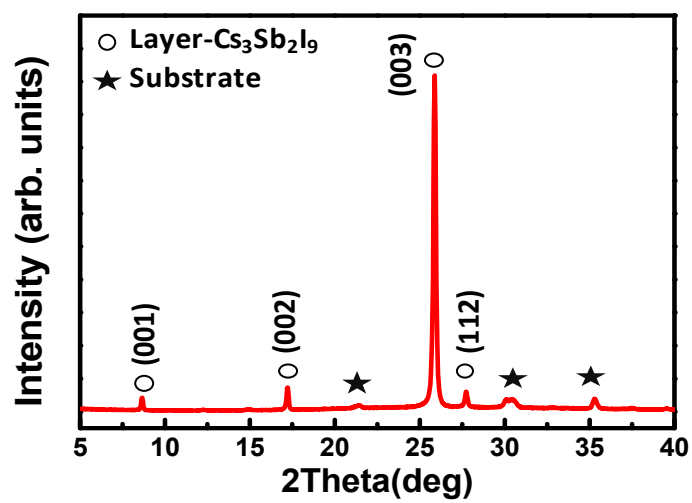
**Supplementary Figure 11.** Data retention characteristics of the dimer-Cs<sub>3</sub>Sb<sub>2</sub>I<sub>9</sub> RSM at LRS and HRS.



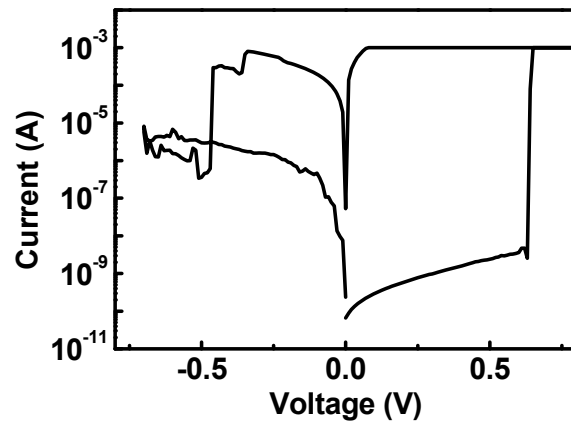
**Supplementary Figure 12.** (a) Applied pulse scheme. (b) Endurance of the dimer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  RSM using 20 ns pulse application.



**Supplementary Figure 13.** (a) Cross-sectional SEM image of the layer-Cs<sub>3</sub>Sb<sub>2</sub>I<sub>9</sub> film. (b) Plan-view SEM image of the layer-Cs<sub>3</sub>Sb<sub>2</sub>I<sub>9</sub> film. (c) AFM image of the surface of the layer-Cs<sub>3</sub>Sb<sub>2</sub>I<sub>9</sub> film. (d) Magnified AFM image of layer-Cs<sub>3</sub>Sb<sub>2</sub>I<sub>9</sub>.

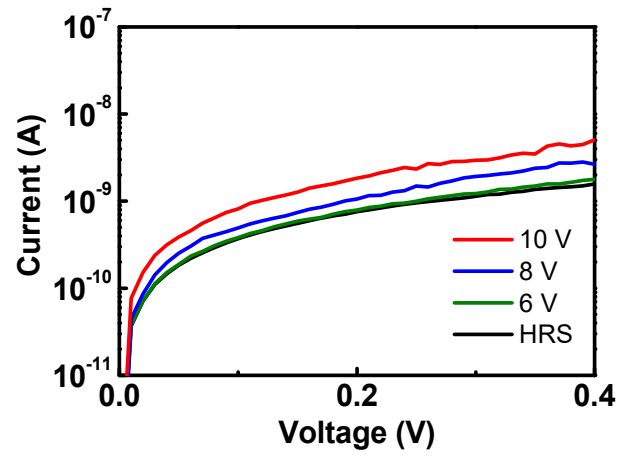


Supplementary Figure 14. XRD pattern of layer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  thin film on ITO.



**Supplementary Figure 15.** *I-V* characteristics of layer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  RSM device.





**Supplementary Figure 16.**  $I$ - $V$  characteristics of the layer- $\text{Cs}_3\text{Sb}_2\text{I}_9$  RSM by application of set pulse (20 ns) with different voltage amplitudes (6 V, 8 V, and 10 V).

**Supplementary Table 1.** Vacancy migration barriers of seven compounds according to two migration paths at final steps.

<b>Compound name</b>	<b>Inter-octahedron barrier (eV)</b>	<b>Intra-octahedron barrier (eV)</b>
Cs <sub>3</sub> Sb <sub>2</sub> I <sub>9</sub> (layer)	0.54	0.24
Cs <sub>3</sub> Sb <sub>2</sub> I <sub>9</sub> (dimer)	0.47	0.37
Cs <sub>3</sub> Bi <sub>2</sub> I <sub>9</sub> (layer)	0.45	0.25
FA <sub>3</sub> Sb <sub>2</sub> I <sub>9</sub> (dimer)	1.2	0.79
CsPdBr <sub>3</sub>	0.44	0.14
GA <sub>3</sub> Sb <sub>2</sub> Br <sub>9</sub> (layer)	0.96	0.34
FA <sub>3</sub> Sb <sub>2</sub> I <sub>9</sub> (layer)	1.04	0.32

**Supplementary Table 2.** Switching speed of HP RSM devices.

<b>Device structure</b>	<b>Switching speed</b>	<b>Reference</b>
<b>Au/Cs<sub>3</sub>Sb<sub>2</sub>I<sub>9</sub>/ITO</b>	20 ns	This work
<b>Al/CH<sub>3</sub>NH<sub>3</sub>PbI<sub>3</sub>:PVAm·HI/ITO</b>	50 ns	1
<b>Au/CH<sub>3</sub>NH<sub>3</sub>PbI<sub>3</sub>/FTO</b>	60 ns	2
<b>Au/(CH<sub>3</sub>NH<sub>3</sub>)<sub>3</sub>Bi<sub>2</sub>I<sub>9</sub>/ITO</b>	100 ns	3
<b>Pt/Zr-doped CH<sub>3</sub>NH<sub>3</sub>PbI<sub>3</sub>/FTO</b>	480 ns	4

1. Cao X., *et al.* Enhanced switching ratio and long-term stability of flexible RRAM by anchoring polyvinylammonium on perovskite grains. *ACS Appl. Mater. Interfaces* **11**, 35914-35923 (2019).
2. Ma H., *et al.* Interface state-induced negative differential resistance observed in hybrid perovskite resistive switching memory. *ACS Appl. Mater. Interfaces* **10**, 21755-21763 (2018).
3. Hwang B. & Lee J.-S. Lead-free, air-stable hybrid organic–inorganic perovskite resistive switching memory with ultrafast switching and multilevel data storage. *Nanoscale* **10**, 8578-8584 (2018).
4. He Y., *et al.* Impact of chemical doping on resistive switching behavior in zirconium-doped CH<sub>3</sub>NH<sub>3</sub>PbI<sub>3</sub> based RRAM. *Org. Electron.* **68**, 230-235 (2019).